

Day : Monday
Date: 2/14/2005

Time: 11:14:46


PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = JIN

First Name = SUNGHO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
<u>60547689</u>	Not Issued	020	02/25/2004	ARTICLE COMPRISING METAL OXIDE NANOSTRUCTURES AND METHOD FOR FABRICATING SUCH NANOSTRUCTURES	JIN, SUNGHO
<u>60547459</u>	Not Issued	019	02/25/2004	ARTICLE COMPRISING CARBIDE AND NITRIDE NANO ELECTRON EMITTERS AND FABRICATION METHOD THEREOF	JIN, SUNGHO
<u>60533727</u>	Not Issued	159	12/31/2003	DEVICE COMPRISING A MATERIAL PATTERNED TO EXHIBIT A LOW SECONDARY ELECTRON EMISSION COEFFICIENT AND METHOD FOR FABRICATING SAID DEVICE AND MATERIAL	JIN, SUNGHO
<u>60533725</u>	Not Issued	159	12/31/2003	METHODS AND ARTICLES FOR REMOTE MAGNETICALLY INDUCED TREATMENT OF CANCER AND OTHER DISEASES, AND METHOD FOR OPERATING SUCH ARTICLE	JIN, SUNGHO
<u>60533618</u>	Not Issued	159	12/31/2003	ARTICLES COMPRISING HIGH-ELECTRICAL-CONDUCTIVITY NANOCOMPOSITE MATERIAL AND METHOD FOR FABRICATING SAME	JIN, SUNGHO
<u>60441437</u>	Not Issued	159	01/21/2003	ARTICLE COMPRISING A GATED FIELD EMISSION STRUCTURE WITH CENTRALIZED NANOWIRES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO

<u>60437309</u>	Not Issued	159	12/31/2002	ARTICLE COMPRISING SPACED APART AND ALIGNED NANOWIRES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>60405588</u>	Not Issued	159	08/23/2002	MULTILAYER VACUUM MICROTUBE DEVICE AND METHOD FOR MAKING SUCH DEVICE	JIN, SUNGHO
<u>60405560</u>	Not Issued	159	08/23/2002	CHIP VACUUM MICROTUBE DEVICE AND METHOD FOR MAKING SUCH DEVICE	JIN, SUNGHO
<u>60275257</u>	Not Issued	159	03/12/2001	APPARATUS AND SYSTEMS COMPRISING A METAL-CLAD SUPERCONDUCTIVE BORIDE BODY, AND METHOD FOR PRODUCING SUCH BODY	JIN, SUNGHO
<u>60264625</u>	Not Issued	159	01/26/2001	PROCESS FOR FABRICATING OXIDATION-RESISTANT BONDING MATERIALS	JIN, SUNGHO
<u>10646600</u>	<u>6803725</u>	150	08/23/2003	ON-CHIP VACUUM MICROTUBE DEVICE AND METHOD FOR MAKING SUCH DEVICE	JIN, SUNGHO
<u>10646502</u>	Not Issued	071	08/23/2003	MICROSCALE VACUUM TUBE DEVICE AND METHOD FOR MAKING SAME	JIN, SUNGHO
<u>10643183</u>	Not Issued	095	08/18/2003	ARTICLE COMPRISING GATED FIELD EMISSION STRUCTURES WITH CENTRALIZED NANOWIRES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>10357159</u>	Not Issued	041	02/03/2003	ARTICLES COMPRISING SPACED-APART NANOSTRUCTURES AND METHODS FOR MAKING THE SAME	JIN, SUNGHO
<u>10357004</u>	<u>6858521</u>	150	02/03/2003	METHOD FOR FABRICATING SPACED-APART NANOSTRUCTURES	JIN, SUNGHO
<u>10350642</u>	Not Issued	030	01/24/2003	MEMS-BASED TWO- DIMENSIONAL E-BEAM NANO LITHOGRAPHY DEVICE AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>10350614</u>	<u>6809465</u>	150	01/24/2003	ARTICLE COMPRISING MEMS- BASED TWO-DIMENSIONAL E-	JIN, SUNGHO

				BEAM SOURCES AND METHOD FOR MAKING THE SAME	
<u>10323522</u>	Not Issued	092	12/18/2002	CHARGE DISSIPATION IN ELECTROSTATICALLY DRIVEN DEVICES	JIN, SUNGHO
<u>10262462</u>	Not Issued	041	09/30/2002	ULTRA-HIGH-DENSITY INFORMATION STORAGE MEDIA AND METHODS FOR MAKING THE SAME	JIN, SUNGHO
<u>10261217</u>	Not Issued	071	09/30/2002	READ HEAD FOR ULTRA-HIGH-DENSITY INFORMATION STORAGE MEDIA AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>10242389</u>	6776165	150	09/12/2002	MAGNETIC NAVIGATION SYSTEM FOR DIAGNOSIS, BIOPSY AND DRUG DELIVERY VEHICLES	JIN, SUNGHO
<u>10226930</u>	Not Issued	094	08/22/2002	ELECTRO-MECHANICAL DEVICE HAVING A CHARGE DISSIPATION LAYER AND A METHOD OF MANUFACTURE THEREFOR	JIN, SUNGHO
<u>10074128</u>	Not Issued	161	02/12/2002	PROCESS FOR CONTROLLED INTRODUCTION OF DEFECTS IN ELONGATED NANOSTRUCTURES	JIN, SUNGHO
<u>10054499</u>	Not Issued	080	01/22/2002	OPTICAL SYSTEMS COMPRISING CURVED MEMS MIRRORS AND METHODS FOR MAKING SAME	JIN, SUNGHO
<u>10050656</u>	Not Issued	161	01/16/2002	ION IMPLANTED LITHIUM NIOBATE MODULATOR WITH REDUCED DRIFT	JIN, SUNGHO
<u>10050244</u>	Not Issued	161	01/16/2002	LITHIUM NIOBATE WAVEGUIDE DEVICE INCORPORATING LI-TRAPPING LAYERS	JIN, SUNGHO
<u>10046836</u>	Not Issued	094	01/15/2002	OXIDATION-RESISTANT REACTIVE SOLDER AND BRAZES	JIN, SUNGHO
<u>09921223</u>	Not Issued	161	08/02/2001	METHOD FOR FABRICATING A METAL-CLAD SUPERCONDUCTIVE BODY, AND ARTICLE COMPRISING	JIN, SUNGHO

				BODY	
<u>09874838</u>	<u>6639724</u>	150	06/05/2001	DEVICE HAVING A BARRIER LAYER LOCATED THEREIN AND A METHOD OF MANUFACTURE THEREFOR	JIN, SUNGHO
<u>09825016</u>	<u>6618184</u>	150	04/03/2001	DEVICE FOR USE WITH A MICRO-ELECTRO-MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	JIN, SUNGHO
<u>09825005</u>	<u>6704475</u>	150	04/03/2001	MIRROR FOR USE WITH A MICRO-ELECTRO-MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	JIN, SUNGHO
<u>09769193</u>	<u>6711317</u>	150	01/25/2001	RESILIENTLY PACKAGED MEMS DEVICE AND METHOD FOR MAKING SAME	JIN, SUNGHO
<u>09769192</u>	<u>6519075</u>	150	01/25/2001	PACKAGED MEMS DEVICE AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09731493</u>	<u>6574026</u>	150	12/07/2000	MAGNETICALLY PACKAGED OPTICAL MEMS DEVICE AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09731135</u>	Not Issued	161	12/06/2000	METHOD OF MAKING A NOBLE METAL-BASED ALLOY ARTICLE	JIN, SUNGHO
<u>09705350</u>	<u>6442307</u>	150	11/03/2000	SOLDER-PACKAGED OPTICAL MEMS DEVICE AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09685883</u>	<u>6522801</u>	150	10/10/2000	MICRO-ELECTRO-OPTICAL MECHANICAL DEVICE HAVING AN IMPLANTED DOPANT INCLUDED THEREIN AND A METHOD OF MANUFACTURE THEREFOR	JIN, SUNGHO
<u>09643784</u>	<u>6383923</u>	150	08/22/2000	METHOD OF MAKING ARTICLE COMPRISING VERTICALLY NANO-INTERCONNECTED CIRCUIT DEVICES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09642216</u>	<u>6319617</u>	150	08/18/2000	OXIDE-BONDABLE SOLDER	JIN, SUNGHO

<u>09631890</u>	<u>6297592</u>	150	08/04/2000	MICROWAVE VACUUM TUBE DEVICE EMPLOYING GRID-MODULATED COLD CATHODE SOURCE HAVING NANOTUBE EMITTERS	JIN, SUNGHO
<u>09548574</u>	<u>6403233</u>	150	04/13/2000	ARTICLE COMPRISING CREEP-RESISTANT AND STRESS-REDUCING SOLDER	JIN, SUNGHO
<u>09521513</u>	Not Issued	161	03/08/2000	FIELD EMITTING DEVICE COMPRISING NANOSTRUCTURES COATED WITH LOW WORK-FUNCTION FILM AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09512873</u>	Not Issued	161	02/25/2000	PROCESS FOR CONTROLLED GROWTH OF CARBON NANOTUBES	JIN, SUNGHO
<u>09500855</u>	<u>6299703</u>	150	02/09/2000	PROCESS FOR FABRICATING IMPROVED IRON-COBALT MAGNETOSTRICTIVE ALLOY AND ARTICLE COMPRISING ALLOY	JIN, SUNGHO
<u>09484627</u>	Not Issued	161	01/18/2000	ARTICLE COMPRISING IMPROVED NOBLE METAL-BASED ALLOYS AND METHODS FOR MAKING THE SAME	JIN, SUNGHO
<u>09483297</u>	<u>6465132</u>	150	01/14/2000	ARTICLE COMPRISING SMALL DIAMETER NANOWIRES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09426453</u>	<u>6297063</u>	150	10/25/1999	IN-SITU NANO-INTERCONNECTED CIRCUIT DEVICES AND METHOD FOR MAKING THE SAME	JIN, SUNGHO
<u>09354928</u>	<u>6322713</u>	150	07/15/1999	NANOSCALE CONDUCTIVE CONNECTORS AND METHOD FOR MAKING SAME	JIN, SUNGHO
<u>09072248</u>	<u>6326685</u>	150	05/04/1998	LOW THERMAL EXPANSION COMPOSITE COMPRISING BODIES OF NEGATIVE CTE MATERIAL DISPOSED WITHIN A POSITIVE CTE MATRIX	JIN, SUNGHO
<u>08771369</u>	Not Issued	020	12/16/1996	FIELD EMISSION DEVICES HAVING CORRUGATED	JIN, SUNGHO

				SUPPORT PILLARS WITH DISCONTINUOUS CONDUCTIVE COATING	
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<input type="text" value="JIN"/>	<input type="text" value="SUNGHO"/>	<input type="button" value="Search"/>

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Day : Monday
Date: 2/14/2005


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Time: 11:15:05

Inventor Name Search Result

Your Search was:

Last Name = MAVOORI

First Name = HAREESH

Application#	Patent#	Status	Date Filed	Title	Inventor Name 36
<u>60275257</u>	Not Issued	159	03/12/2001	APPARATUS AND SYSTEMS COMPRISING A METAL-CLAD SUPERCONDUCTIVE BORIDE BODY, AND METHOD FOR PRODUCING SUCH BODY	MAVOORI, HAREESH
<u>60264625</u>	Not Issued	159	01/26/2001	PROCESS FOR FABRICATING OXIDATION-RESISTANT BONDING MATERIALS	MAVOORI, HAREESH
<u>60120697</u>	Not Issued	159	02/19/1999	MAGNETICALLY CONTROLLED WAVELENGTH-SELECTIVE OPTICAL CROSS-CONNECT	MAVOORI, HAREESH
<u>10054499</u>	Not Issued	080	01/22/2002	OPTICAL SYSTEMS COMPRISING CURVED MEMS MIRRORS AND METHODS FOR MAKING SAME	MAVOORI, HAREESH
<u>10046836</u>	Not Issued	094	01/15/2002	OXIDATION-RESISTANT REACTIVE SOLDERS AND BRAZES	MAVOORI, HAREESH
<u>09921223</u>	Not Issued	161	08/02/2001	METHOD FOR FABRICATING A METAL-CLAD SUPERCONDUCTIVE BODY, AND ARTICLE COMPRISING BODY	MAVOORI, HAREESH
<u>09874838</u>	<u>6639724</u>	150	06/05/2001	DEVICE HAVING A BARRIER LAYER LOCATED THEREIN AND A METHOD OF MANUFACTURE THEREFOR	MAVOORI, HAREESH
<u>09825016</u>	<u>6618184</u>	150	04/03/2001	DEVICE FOR USE WITH A MICRO-ELECTRO-MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	MAVOORI, HAREESH

<u>09825005</u>	<u>6704475</u>	150	04/03/2001	MIRROR FOR USE WITH A MICRO-ELECTRO-MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	MAVOORI, HAREESH
<u>09769193</u>	<u>6711317</u>	150	01/25/2001	RESILIENTLY PACKAGED MEMS DEVICE AND METHOD FOR MAKING SAME	MAVOORI, HAREESH
<u>09685883</u>	<u>6522801</u>	150	10/10/2000	MICRO-ELECTRO-OPTICAL MECHANICAL DEVICE HAVING AN IMPLANTED DOPANT INCLUDED THEREIN AND A METHOD OF MANUFACTURE THEREFOR	MAVOORI, HAREESH
<u>09642216</u>	<u>6319617</u>	150	08/18/2000	OXIDE-BONDABLE SOLDER	MAVOORI, HAREESH
<u>09548574</u>	<u>6403233</u>	150	04/13/2000	ARTICLE COMPRISING CREEP-RESISTANT AND STRESS-REDUCING SOLDER	MAVOORI, HAREESH
<u>09500855</u>	<u>6299703</u>	150	02/09/2000	PROCESS FOR FABRICATING IMPROVED IRON-COBALT MAGNETOSTRICTIVE ALLOY AND ARTICLE COMPRISING ALLOY	MAVOORI, HAREESH
<u>09466449</u>	<u>6306516</u>	150	12/17/1999	ARTICLE COMPRISING OXIDE-BONDABLE SOLDER	MAVOORI, HAREESH
<u>09271642</u>	<u>6597481</u>	150	03/18/1999	CONTROLLABLE WAVELENGTH-SELECTIVE OPTICAL CROSS-CONNECT	MAVOORI, HAREESH
<u>09261346</u>	<u>6153020</u>	150	03/03/1999	PROCESS FOR FABRICATING IMPROVED IRON-COBALT MAGNETOSTRICTIVE ALLOY AND ARTICLE COMPRISING ALLOY	MAVOORI, HAREESH
<u>09255582</u>	<u>6154471</u>	150	02/22/1999	MAGNETICALLY TUNABLE AND LATCHABLE BROAD-RANGE SEMICONDUCTOR LASER	MAVOORI, HAREESH
<u>09255299</u>	<u>6301425</u>	150	02/22/1999	MAGNETICALLY TUNABLE OPTICAL ATTENUATOR AND METHOD OF ATTENUATING SIGNALS	MAVOORI, HAREESH
<u>09237124</u>	<u>6181852</u>	150	01/26/1999	OPTICAL GRATING DEVICE WITH VARIABLE COATING	MAVOORI, HAREESH
<u>09237123</u>	<u>6169831</u>	150	01/26/1999	METHOD OF MAKING	MAVOORI,

				OPTICAL CHIRPED GRATING WITH AN INTRINSICALLY CHIRPED GRATING AND EXTERNAL GRADIENT	HAREESH
<u>09231566</u>	<u>6225801</u>	150	01/14/1999	ARTICLE COMPRISING ELECTRONIC CIRCUITS AND DEVICES WITH MAGNETICALLY PROGRAMMABLE ELECTRICAL RESISTANCE	MAVOORI , HAREESH
<u>09162325</u>	<u>6154590</u>	150	09/28/1998	WAVELENGTH-TUNABLE DEVICES AND SYSTEMS COMPRISING FLEXED OPTICAL GRATINGS	MAVOORI , HAREESH
<u>09162324</u>	<u>6148128</u>	150	09/28/1998	PASSIVELY TEMPERATURE-COMPENSATED WAVELENGTH-TUNABLE DEVICE COMPRISING FLEXED OPTICAL GRATINGS AND COMMUNICATION SYSTEMS USING SUCH DEVICES	MAVOORI , HAREESH
<u>09159907</u>	<u>6122421</u>	150	09/24/1998	MAGNETOSTRICTIVE WAVELENGTH-SHIFTING DEVICES AND OPTICAL COMMUNICATION SYSTEMS COMPRISING SAME	MAVOORI , HAREESH
<u>09159380</u>	<u>6055348</u>	150	09/23/1998	TUNABLE GRATING DEVICE AND OPTICAL COMMUNICATION DEVICES AND SYSTEMS COMPRISING SAME	MAVOORI , HAREESH
<u>09159178</u>	<u>6148127</u>	150	09/23/1998	TUNABLE DISPERSION COMPENSATOR AND OPTICAL SYSTEM COMPRISING SAME	MAVOORI , HAREESH
<u>09158672</u>	<u>5999546</u>	150	09/22/1998	MAGETICALLY TUNABLE LASER WITH WAVELENGTH LATCHABILITY AND OPTICAL COMMUNICATION SYSTEM COMPRISING SUCH LASER	MAVOORI , HAREESH
<u>09157967</u>	<u>6102582</u>	150	09/21/1998	ARTICLE COMPRISING CONTROLLABLE OPTICAL CONNECTORS	MAVOORI , HAREESH
<u>09141906</u>	<u>6128427</u>	150	08/28/1998	ARTICLES AND SYSTEMS COMPRISING DIGITALLY	MAVOORI , HAREESH

				TUNNABLE OPTICAL GRATINGS	
<u>09097549</u>	<u>6085016</u>	150	06/15/1998	MAGNETICALLY CONTROLLED VARIABLE OPTICAL ATTENUATOR	MAVOORI, HAREESH
<u>09072248</u>	<u>6326685</u>	150	05/04/1998	LOW THERMAL EXPANSION COMPOSITE COMPRISING BODIES OF NEGATIVE CTE MATERIAL DISPOSED WITHIN A POSITIVE CTE MATRIX	MAVOORI, HAREESH
<u>09062339</u>	<u>6101301</u>	150	04/17/1998	TEMPERATURE-COMPENSATED OPTICAL FIBER GRATINGS WITH FINE WAVELENGTH TUNING	MAVOORI, HAREESH
<u>09059858</u>	<u>6205264</u>	150	04/14/1998	OPTICAL ASSEMBLY WITH IMPROVED DIMENSIONAL STABILITY	MAVOORI, HAREESH
<u>09020206</u>	<u>6141470</u>	150	02/06/1998	MAGNETICALLY RECONFIGURABLE OPTICAL GRATING DEVICES AND COMMUNICATION SYSTEMS	MAVOORI, HAREESH
<u>08961542</u>	<u>6049155</u>	150	10/27/1997	THERMALLY TUNABLE SURFACE ACOUSTIC WAVE DEVICES	MAVOORI, HAREESH

Inventor Search Completed: No Records to Display.

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Last Name	First Name
MAVOORI	HAREESH

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Day : Monday
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Inventor Name Search Result

Your Search was:

Last Name = RYF

First Name = ROLAND

Application#	Patent#	Status	Date Filed	Title	Inventor Name 11
<u>60601569</u>	Not Issued	020	08/13/2004	MULTIPLE ACCESS FREE SPACE LASER COMMUNICATION METHOD AND APPARATUS	RYF, ROLAND
<u>10780248</u>	Not Issued	030	02/17/2004	1 X N WAVELENGTH SELECTIVE SWITCH	RYF, ROLAND
<u>10666058</u>	Not Issued	071	09/18/2003	OPTICAL DEVICE WITH CONFIGURABLE CHANNEL ALLOCATION	RYF, ROLAND
<u>10396238</u>	Not Issued	061	03/25/2003	OPTICAL FILTERING METHOD AND APPARATUS	RYF, ROLAND
<u>10054499</u>	Not Issued	080	01/22/2002	OPTICAL SYSTEMS COMPRISING CURVED MEMS MIRRORS AND METHODS FOR MAKING SAME	RYF, ROLAND
<u>09896339</u>	6757458	150	06/29/2001	OPTICAL MEMS SWITCH WITH CONVERGING BEAMS	RYF, ROLAND
<u>09896085</u>	Not Issued	092	06/29/2001	IMAGING TECHNIQUE FOR USE WITH OPTICAL MEMS DEVICES	RYF, ROLAND
<u>09896005</u>	6647172	150	06/29/2001	IMAGING TECHNIQUE FOR USE WITH OPTICAL MEMS DEVICES	RYF, ROLAND
<u>09895949</u>	6704476	150	06/29/2001	OPTICAL MEMS SWITCH WITH IMAGING SYSTEM	RYF, ROLAND
<u>09825016</u>	6618184	150	04/03/2001	DEVICE FOR USE WITH A MICRO-ELECTRO-MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	RYF, ROLAND
<u>09825005</u>	6704475	150	04/03/2001	MIRROR FOR USE WITH A MICRO-ELECTRO-	RYF, ROLAND

				MECHANICAL SYSTEM (MEMS) OPTICAL DEVICE AND A METHOD OF MANUFACTURE THEREFOR	
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Inventor Search Completed: No Records to Display.

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<input type="text" value="RYF"/>	<input type="text" value="ROLAND"/>	<input type="button" value="Search"/>

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Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	762	(mirror or reflector) with curv\$ with (tilt\$6 or pivot\$6)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:33
S2	345	S1 and ("385"/\$.ccls. or "359"/\$.ccls.)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:34
S3	141	S2 and (layer\$6 or substrat\$6)	US-PGPUB; USPAT	OR	ON	2005/02/11 10:04
S4	1	"20030138213" and (actu\$6 with layer)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:25
S5	0	(MEM with dop\$6 with curv\$6) same mirror	USPAT	OR	ON	2004/01/09 10:39
S6	106	MEM with dop\$6	USPAT	OR	ON	2004/01/09 10:28
S7	18	(MEM with dop\$6) and (mirror or relect\$6)	USPAT	OR	ON	2003/09/12 15:23
S8	1	MEM with dop\$6 with curv\$6	USPAT	OR	ON	2003/09/12 15:23
S9	1	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu."\$8)) and (curvature with radius)	USPAT	OR	ON	2004/01/08 11:41
S10	9	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu."\$8)) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:30
S11	1	"20030138213"	US-PGPUB; USPAT	OR	ON	2004/01/08 11:51
S12	9	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S13	7	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)) and "mu.m"	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S14	7	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)) and "mu.m"\$8	US-PGPUB; USPAT	OR	ON	2004/01/10 17:33
S15	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/01/08 14:27
S16	2	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	USPAT	OR	ON	2004/01/09 10:14

S17	5	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:15
S18	8	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	US-PGPUB; USPAT	OR	ON	2004/08/28 15:00
S19	1	((MEM or MOEM) with dop\$6) with ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))	USPAT	OR	ON	2004/01/09 10:45
S20	510	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)	USPAT	OR	ON	2004/01/09 10:31
S21	1005	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:45
S22	22	(MEMS or Moems) and (dop\$6 with curvature).	US-PGPUB; USPAT	OR	ON	2004/01/09 10:40
S23	161	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S24	123	((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S25	51	((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8) and (dop\$6 same substrate)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:25
S26	25	ryf.in.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09
S27	1	"5618474".pn.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09

S28	6221	((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon	US-PGPUB; USPAT	OR	ON	2004/01/10 17:34
S29	175	((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon with value	US-PGPUB; USPAT	OR	ON	2004/01/10 17:39
S30	395	((coeff\$8 with therm\$6 with expan\$6) or CTE) with gold	US-PGPUB; USPAT	OR	ON	2004/01/10 17:47
S31	15	((coeff\$8 with therm\$6 with expan\$6) or CTE) same (dielectric\$6 with (layer\$4 or stack\$6) with mirror)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:16
S32	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:29
S33	1	"6525880".pn. and (mirror same coat\$6)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:13
S34	1558	mirror with coat\$6 with dielectric	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S35	144	(mirror with coat\$6 with dielectric) and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S36	46	(mirror with coat\$6 with dielectric) and (mirror same (coeff\$8 with therm\$6 with expan\$6))	US-PGPUB; USPAT	OR	ON	2004/01/10 18:17
S37	2488	385/16.ccls. or 385/18.ccls. or 385/47.ccls. or 359/578.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 19:10
S38	42	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter))	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S39	21	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter)) and (micrometers or mu)	US-PGPUB; USPAT	OR	ON	2004/11/16 13:40
S40	1	"20030138213"	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S41	0	("2003/0138213").URPN.	USPAT	OR	OFF	2004/11/16 13:44
S42	789	(mirror or reflector) with curv\$ with (tilt\$6 or pivot\$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S43	364	S42 and ("385"/\$.ccls. or "359"/\$.ccls.)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S44	16	S43 and (layer\$6 or substrat\$6) and (dop\$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:12
S45	1	"6594059".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:39
S46	1	"20030011864"	US-PGPUB; USPAT	OR	ON	2004/11/29 11:03
S47	0	sag with curvature with mirror same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:04
S48	0	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6) same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:05

S49	6	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6) and MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S50	149	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S51	143	S50 not S49	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S52	2	spoil\$6 with sag\$6 with cavity same (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:35
S53	35	(mems with fabry) and ((mirror\$6 or reflect\$6) with (mm or nm or micrometer or millimeter or nanometer))	US-PGPUB; USPAT	OR	ON	2004/11/29 11:58
S54	324	fabry with cavity with length same (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:59
S55	50	fabry with cavity with length same (mirror\$6 or reflect\$6) same (mm or nm or micrometer or millimeter or nanometer)	US-PGPUB; USPAT	OR	ON	2004/11/29 12:00
S56	333	MEM with tilt\$6 with (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2005/02/11 10:06
S57	120	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$6 or curv\$6 or curvat\$6 or round\$6))	US-PGPUB; USPAT	OR	ON	2005/02/11 10:08
S59	15923	199807???.fd.	US-PGPUB; USPAT	OR	ON	2005/02/11 10:53
S60	149	199807???.fd. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:00
S61	30	"20020122".fd. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:01
S62	0	"200201\$\$".fd. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:01
S63	417	200201???.fd. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:03
S64	0	200201???.fd. and "2001".ay. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:04
S65	0	200201???.fd. and "2001".ay.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:05
S66	412172	200201???.fd. or "2001".ay.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:06
S67	33693	200201???.fd. or "2001".ay. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:07
S68	414473	200201???.fd. or "2001".ay. or "2000".ay. and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:07
S69	7710	(200201???.fd. or "2001".ay. or "2000".ay.) and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:10

S70	417	(200201??fd. or 2000-2001.ay.) and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:09
S71	18889	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/11 11:12
S73	56	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay. or 197?.ay.) and S57	US-PGPUB; USPAT	OR	ON	2005/02/11 11:15
S74	120	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$6 or curv\$6 or curvat\$6 or round\$6))	US-PGPUB; USPAT	OR	ON	2005/02/11 11:25
S75	98	S74 and (optic\$6 with fiber)	US-PGPUB; USPAT	OR	ON	2005/02/11 11:21
S76	56	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and S74	US-PGPUB; USPAT	OR	ON	2005/02/11 11:26
S77	106	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6))	US-PGPUB; USPAT	OR	ON	2005/02/12 13:49
S78	47	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and S77	US-PGPUB; USPAT	OR	ON	2005/02/12 13:51
S79	2	("6594059").URPN.	USPAT	OR	OFF	2005/02/11 17:24
S80	36	359/846.ccls. and "2004"	US-PGPUB; USPAT	OR	ON	2005/02/12 13:38
S81	9	359/846.ccls. and "2005"	USPAT	OR	ON	2005/02/12 13:39
S82	5	359/226.ccls. and "2005"	USPAT	OR	ON	2005/02/12 13:46
S83	16	359/226.ccls. and "2004"	USPAT	OR	ON	2005/02/12 13:46
S84	13	S83 not S82	USPAT	OR	ON	2005/02/12 13:40
S85	12	359/223.ccls. and "2005"	USPAT	OR	ON	2005/02/12 13:46
S86	297	(MEM or actuator) with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6))	US-PGPUB; USPAT	OR	ON	2005/02/12 13:49
S87	137	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and S86	US-PGPUB; USPAT	OR	ON	2005/02/12 13:51
S88	106	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6))	US-PGPUB; USPAT	OR	ON	2005/02/12 14:14
S89	47	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and S88	US-PGPUB; USPAT	OR	ON	2005/02/12 13:51
S90	90	(200201??fd. or "2001".ay. or "2000".ay. or 199?.ay.) and S86 not S89	US-PGPUB; USPAT	OR	ON	2005/02/12 13:57
S91	15	S90 and (radi\$4 near2 curvat\$6)	US-PGPUB; USPAT	OR	ON	2005/02/12 13:58

S92	2	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6)) and 359/223.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/12 14:14
S93	1	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6)) and 359/846.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/12 14:18
S94	0	MEM with tilt\$6 with (mirror\$6 or reflect\$6) and ((mirror\$6 or reflect\$6) with (radi\$3 or curv\$6 or curvat\$6 or round\$6)) and 359/850.ccls.	US-PGPUB; USPAT	OR	ON	2005/02/12 14:14